



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/056,154 Confirmation No.: 2279
First-named Inventor: Fortin, Vincent Filing Date: 23 January 2002
Group Art Unit: 2823 Examiner: Lee, Hsien Ming
Attorney Docket No.: M-12524 US
Title: Cobalt Silicide Fabrication Using Protective Titanium
Assignee(s): Mosel Vitelic, Inc.

Mountain View, California
22 September 2005

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**SUPPLEMENTAL
INFORMATION DISCLOSURE STATEMENT**

Sir:

In reviewing the file for the above patent application, Applicant's Attorney determined that the citation information for reference AK, a document entitled "Applied Materials Launches Advanced Cobalt Solution for Nano-Chip Manufacturing", in the Information Disclosure Statement submitted 25 March 2002 for this application was incomplete and partially wrong. Enclosed is a substitute PTO Form 1449 which lists this document with corrected citation information. Please use the corrected citation information in printing the patent that issues on the above application.

Hopwood, also listed on the accompanying substitute PTO Form 1449, was cited in the Response submitted 6 June 2005 to show that techniques for performing ionized physical vapor deposition include ionized sputtering and ionized evaporation.

Citation of the listed documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;

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2. a representation that a search has been made; or
3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in 37 CFR 1.56(b).

Please place this paper and the enclosures in the PTO file for the above application.

Please telephone Applicants' Attorney at 650-964-9767 if there are any questions.

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Respectfully submitted,

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U.S. Department of Commerce, Patent and Trademark Office			Atty Docket No.		Application No.		
SEP 22 2005			M-12524 US		10/056,154		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT			Applicant(s)		Confirmation No.		
Substitute Form PTO-1449			Fortin, Vincent		2279		
SEP 22 2005			Filing Date		Group		
			23 January 2002		2823		
U.S. Patent Documents							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
Foreign Patent Documents							
							Translation
	AM						
	AN						
	AO						
	AP						
	AQ						
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
	AR	Hopwood, "Ionized physical vapor deposition of integrated circuit interconnects", <u>Physics of Plasmas</u> , May 1998, pp. 1624 - 1631					
	AS	"Applied Materials Launches Advanced Cobalt Solution for Nano-Chip Manufacturing", Business Wire, Applied Materials, http://www.businesswire.com/cgi-bin/cnn-storydisplay.cgi?story=www/between/webboc/bw.1204...1 , Dec. 4, 2001, 1 page					
	AT						
Examiner		Date Considered					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							